

PATENT APPLICATION

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In re the Application of

Masashi UEDA et al.

Application No.: 09/830,879

Docket No.: 109426

Filed: May 2, 2001

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SEP 14 2001

TC 1700

For: INTERNAL ELECTRODE TYPE PLASMA PROCESSING APPARATUS AND
PLASMA PROCESSING METHOD


REQUEST FOR CORRECTION OF PALM RECORDS

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Sir:

Attached is a photocopy of the original filing receipt on which errors have been corrected in red. These errors are being brought to the attention of the Patent and Trademark Office so that it may correct its records.

Respectfully submitted,

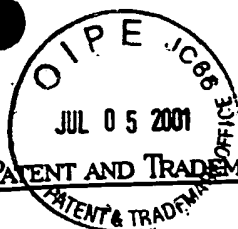

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APPLICATION NUMBER	FILING DATE	GRP ART UNIT	FIL FEE REC'D	ATTY. DOCKET NO	DRAWINGS	TOT CLAIMS	IND CLAIMS
09/830,879	05/02/2001	1734	1100	109426	7	18	6

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CONFIRMATION NO. 5332

FILING RECEIPT



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Date Mailed: 06/08/2001

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Applicant(s)

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 Assignment for Published Patent Application
 ANELVA CORPORATION

Domestic Priority data as claimed by applicant

THIS APPLICATION IS A 371 OF PCT/JP00/06189 09/11/2000

Foreign Applications

 JAPAN 11/255219 09/09/1999
 JAPAN 2000/56584 03/02/2000

Projected Publication Date: N/A

Non-Publication Request: No

Early Publication Request: No

Title

 Internal electrode type plasma
 inner-electrode-plasma processing apparatus and method of plasma processing method

Preliminary Class

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